Substitute for form 1449A/PTO

INFORMATION DISCLOSURE STATEMENT BY APPLICANT

(Use as many sheets as necessary)

Sheet 1 of 1

Complete if Known	
Application Number	09/945497
Filing Date	August 30, 2001
First Named Inventor	Sandhu, Gurtej
Group Art Unit	2822
Examiner Name	Rose, Kiesha

Attorney Docket No: 303.541US3

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